

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Dapeng Wang

**Serial No.:** Not Yet Assigned

**Filed:** December 5, 2003

**For:** DEFORMABLE PAD FOR  
CHEMICAL MECHANICAL POLISHING

**Confirmation No.:** Unknown

**Examiner:** Unknown

**Group Art Unit:** Unknown

**Attorney Docket No.:** 2269-3579.2US  
(98-0062.02/US)

**NOTICE OF EXPRESS MAILING**

Express Mail Mailing Label Number: EV326923337US

Date of Deposit with USPS: December 5, 2003

Person making Deposit: Christopher Haughton

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

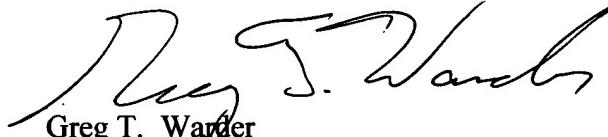
The present application is a divisional of application Serial No. 09/617,692, filed July 17, 2000, pending.

Pursuant to M.P.E.P. 2001.06(b), the Examiner is respectfully requested to consider the information of record in the prior application, and to confirm in the first Office Action on the merits that such art has in fact been reviewed. A PTO-1449 form listing all of the information of record in the prior application is enclosed herewith.

**Attorney Docket N .: 2269-3579.2US**

This Information Disclosure Statement is filed within three (3) months of the filing date of the above-identified application, and no certification pursuant to 37 C.F.R. § 1.97(c) or a fee pursuant to 37 C.F.R. 1.17(p) is required.

Respectfully submitted,



Greg T. Warner  
Registration No. 50,208  
Attorney for Applicant(s)  
TRASKBRITT  
P.O. Box 2550  
Salt Lake City, Utah 84110-2550  
Telephone: 801-532-1922

Date: December 5, 2003

GTW/ps:ljb

Enclosures: Form PTO-1449

Document in ProLaw

Form PTO-1449  INFORMATION DISCLOSURE CITATION IN AN APPLICATION  (Use several sheets if necessary)			Docket Number (Optional) <b>3579.2US (98-0062.02/US)</b>	Application Number <b>N t Y t Assigned</b>			
			Applicant <b>Dapeng Wang</b>				
			Filing Date <b>December 5, 2003</b>	Group Art Unit <b>Unknown</b>			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS		
	5,232,875	08/1993	Tuttle et al.				
	5,514,245	05/1996	Doan et al.				
	5,624,299	04/1997	Shendon				
	5,664,989	09/1997	Nakata et al.				
	5,692,947	12/1997	Talieh et al.				
	5,692,950	12/1997	Rutherford et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
	57023965 A	02/1982	JP				
	58045861 A	03/1983	JP				
<b>OTHER DOCUMENTS</b>						(Including Author, Title, Date, Pertinent Pages, Etc.)	
		Wang et al., Von Mises Stress in Chemical-Mechanical Polishing Processes, J. Electrochem. Soc., Vol. 144, No. 3, March 1997 pp. 1121-27.					
EXAMINER			DATE CONSIDERED				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							